

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional)

OKI.390C

Application Number

NEW

Applicant(s)

Kazuya Hizawa

Filing Date

February 19, 2004

Group Art Unit

Unknown

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
OK	A	2002/0061639	05/2002	Itonaga			
OK	B	6,054,386	04/2000	Prabhakar			

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
OK	C	2000-082811	03/21/2000	Japan				
OK	D	10-335261	12/18/1998	Japan				

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

OK	E	J. Fukuhara et al., "The Orientation of Blanket W-CVD on the underlayer Ti/TiN studied by XRD," ADMETA 2000: Asian Session, pages 71 and 72.
OK	F	Kunihiro Fujii et al., "Sub-Quarter Micron Titanium Salicide Technology With In-Situ Silicidation Using High-Temperature Sputtering," 1995 Symposium on VLSI Technology Digest of Technical Papers, pages 57 and 58.

EXAMINER

Christy Kovack

DATE CONSIDERED

5/10/05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.